

U.S. Department of Commerce, Patent and Trademark	Atty. Docket No.	Application No.
INFORMATION DISCLOSURE STATEMENT BY APPLICANT	TNCR.152US7	10/627,402
	Applicant(s)	Conf. No.
Use several sheets if necessary)	M. Vaez-Iravani et al.	2861
	Filing Date	Group
	July 24, 2003	2877

U.S. Patent Documents

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
HP	AA	4,558,949	12/85	Uehara et al.			
HP	AB	4,893,932	1/1990	Knollenberg			
HP	AC	5,058,982	10/1991	Katzir			
HP	AD	5,712,701	1/98	Dementi et al.			
HP	AE	5,929,983	7/99	Lu			
HP	AF	6,118,525	9/00	Fossey et al.			
HP	AG	6,169,601	1/01	Eremin et al.			

U.S. Published Patent Application Documents

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate

Foreign Patent Documents

							Translation	
		Document	Date	Country	Class	Subclass	Yes	No
HP	AH	WO97/33158	9/1997	International			X	
HP	AI	EP0624787	11/1994	Europe			Abstract	
HP	AJ	DE4123916	1/1992	German			Abstract	
HP	AK	WO97/12226	4/1997	International			X	

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

HP	AL	"Surface Inspection System for Estimation of Wafer," Y. Yatsugake et al., <i>Hitachi Electronics Engineering Technical Report</i> , Vol. 11, January 1996, pp. 21-26
HP	AM	Figure, Hitachi Electronics Engineering Co., Ltd., presented by Etsuro Morita of Mitsubishi Materials Silicon Corp. in a presentation entitled "Exploration of COP and COP Defect Crystal Originated 'Particles'." at the 6 th International Workshop on 300 Millimeter Wafers on 12/5/1996 in Makuhari, Japan
HP	AN	Partial European Search Report dated October 18, 2000

Examiner

Date Considered

1/6/05

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.

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IA	AA	4,589,773	5/86	Ido et al.			
IA	AB	4,740,079	04/88	Koizumi et al.			
IA	AC	4,966,457	10/90	Hayano et al.			
IA	AD	5,125,741	6/92	Okada et al.			
IA	AE	5,189,481	2/93	Jann et al.			
IA	AF	5,245,403	9/93	Kato et al.			
IA	AG	5,465,145	11/95	Nakashige et al.			

U.S. Published Patent Application Documents							
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
				None			

Foreign Patent Documents								
							Translation	
		Document	Date	Country	Class	Subclass	Yes	No
IA	AH	WO96/15354	9/25/96	International			X	
IA	AI	WO97/04134	3/5/97	International			X	
IA	AJ	WO99/14575	3/99	International			X	

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)		
IA	AK	Search Report Corresponding to PCT Application No. PCT/US98/19564 issued by the International Patent Office on February 8, 1999.

Examiner	<i>[Signature]</i>	Date Considered	1/6/05
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AP	AA	4,395,126	7/83	Kramer	1	1	
AP	AB	4,449,818	5/84	Yamaguchi	1	1	
AP	AC	4,540,286	9/85	Satake et al.	1	1	
AP	AD	4,598,997	7/86	Steigmeier et al.	1	1	
AP	AE	4,669,875	6/87	Shiba et al.	1	1	
AP	AF	4,794,265	12/27/88	Quackenbos et al.	1	1	
AP	AG	4,861,164	8/89	West	1	1	
AP	AH	4,898,471	2/6/90	Stonestrom et al.	1	1	
AP	AI	RE: 33,956	6/92	Line et al.	1	1	
AP	AJ	5,155,372	10/92	Bowen et al.	1	1	
AP	AK	5,245,403	9/93	Kato et al.	1	1	
AP	AL	5,389,794	2/14/1995	Allen et al.	1	1	
AP	AM	5,463,459	10/95	Morioka et al.	1	1	
AP	AN	5,486,919	1/96	Tsuji et al.	1	1	
AP	AO	5,530,550	6/25/96	Nikoonahad et al.	1	1	
AP	AP	5,672,885	9/97	Allen et al.	1	1	
AP	AQ	5,672,885	9/97	Allen et al.	1	1	
AP	AR	5,940,175	8/99	Sun	1	1	
AP	AS	6,084,664	7/00	Matsumoto et al.	1	1	
AP	AT	6,201,601	3/01	Vaez-Iravani et al.	1	1	

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